

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re PATENT APPLICATION of :
Byeong-Cheol Lee et al. : Group Art Unit: 2851
Application No.: 10/655,309 : Examiner: Rutledge, Della J.
Filed: September 5, 2003 :

EXPOSURE CONDITION CONTROL IN SEMICONDUCTOR
MANUFACTURING APPARATUS HAVING LIGHT ENERGY
INSPECTING APPARATUS

**AMENDMENT AND REQUEST FOR
RECONSIDERATION**

U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria, VA 22304

Sir:

In response to the Office Action dated December 16, 2004, the Applicants submit the following remarks and arguments regarding the above-identified application as follows:

Claim Amendments begin on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.